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**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1753**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM FORMATION, METHOD FOR  
ELECTRODE FORMATION, AND APPARATUS FOR ELECTRODEPOSITED FILM  
FORMATION

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the July 14, 2004, Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**